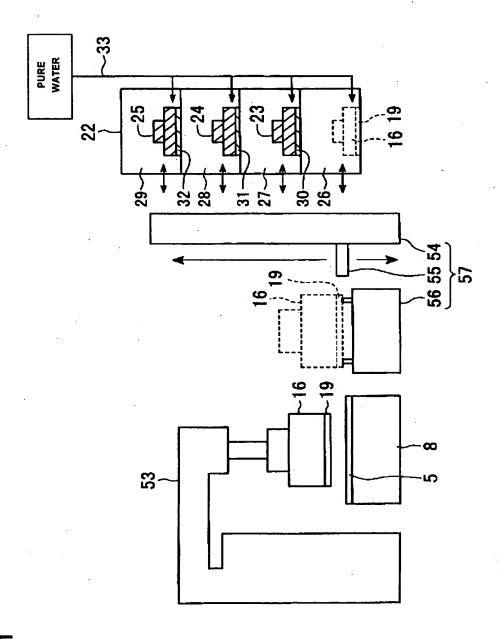
Title: CMP APPARATUS, CMP POLISHING METHOD, SEMICONDUCTOR DEVICE AND ITS MANUFACTURING METHOD

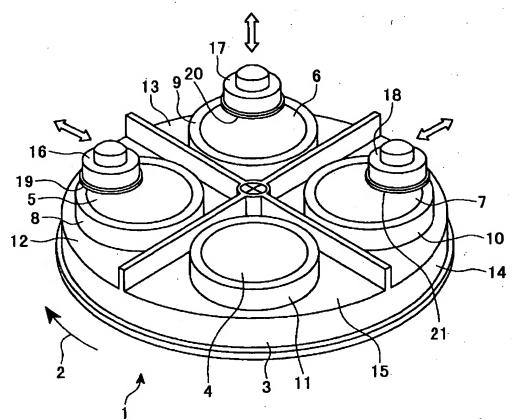
Inventor: Junichi TAKEUCHI Atty. Ref.: 9319S-000690

1/4



2/4

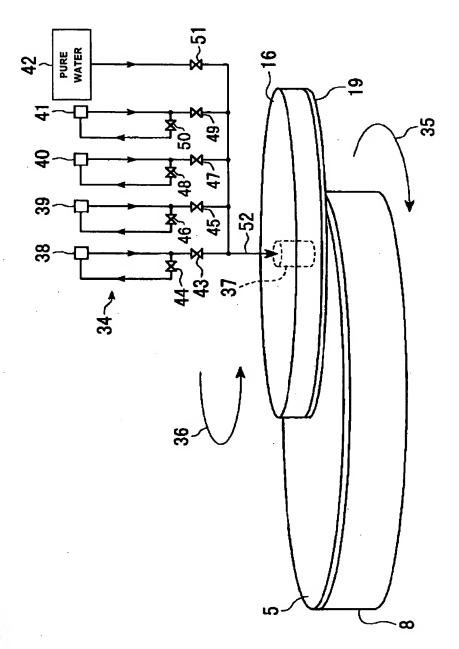
FIG. 2



Title: CMP APPARATUS, CMP POLISHING METHOD, SEMICONDUCTOR DEVICE AND ITS MANUFACTURING METHOD

Inventor: Junichi TAKEUCHI Atty. Ref.: 9319S-000690

3/4



<u>FIG.</u> 3

MANUFACTURING METHOD Inventor: Junichi TAKEUCHI Atty. Ref.: 9319S-000690

FIG. 4 PRIOR ART



